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Examiner Initials*	Cite No.1	Document Number Number-Kind Code ^{2 (f known)}	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	1	US- 4596929	06-24-1986	COATES ET AL.	
	2	03. 4627009	12-02-1986	HOLHES ET AL.	
	3	US- 5179280	01-12-1993	WANG	
	4	US- 5510624	04-23-1996	ZALUZEC	
	5	US- 6025592	02-15-2000		
	<u>_b_</u>	US- 6407850	06-18-2002	Roto et al.	
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STATEMENT BY APPLICANT			ANT	First Named Inventor	WILLIAM E. VANDERLINDE	
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Sheet	2	of	4		Attorney Docket Number	VANDERLINDE-I

		OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS	
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	7	JOSEPH I. 60 D STEIN ex. al., SCANNING ELECTION MICROSCOPY AND X-RAY MICROANALYSIS, 1992, PLENUM PRESS, NEW YORK, APSZ67-270	
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INFORMATION DISCLOSURE STATEMENT

- 1. U.S. Pat. No. 4,596,929, entitled "THREE-STAGE SECONDARY EMISSION

 ELECTRON DETECTION IN ELECTRON MICROSCOPES," discloses a device that uses two
 grids to maximize the amount of secondary emission detected by a scintillator. The present
 invention does not employ two such grids.
- 2. U.S. Pat. No. 4,627,009, entitled "MICROSCOPE STAGE ASSEMBLY AND CONTROL SYSTEM," discloses a device for rotating and tilting a sample in a non-eucentric manner and compensate for the same so that an inspection point is within the field of view. The present invention does not rotate and tilt a sample in a non-eucentric manner and compensate for the same so that an inspection point is within the field of view.
- 3. U.S. Pat. No. 5,179,280, entitled "COMPUTER CONTROL OF THE ELECTRON MICROSCOPE SAMPLE STAGE," discloses a device for tilting a sample so that a plurality of different orientations are displayed stereoscopically with a spot representing a current orientation. The present invention does not tilt a sample so that a plurality of different orientations are displayed stereoscopically with a spot representing a current orientation.
- 4. U.S. Pat. No. 5,510,624, entitled "SIMULTANEOUS SPECIMEN AND STAGE CLEANING DEVICE FOR ANALYTICAL ELECTRON MICROSCOPE," discloses a device for cleaning both a sample stage, a sample, and an interior of an analytical electron microscope.

The present invention does not clean either a sample stage, a sample, or an interior of an analytical electron microscope.

- 5. U.S. Pat. No. 6,025,592, entitled "HIGH TEMPERATURE SPECIMEN STAGE AND DETECTOR FOR AN ENVIRONMENTAL SCANNING ELECTRON MICROSCOPE," discloses a device that can heat a sample to 1500 degrees Celsius. The present invention does not heat a sample to 1500 degrees Celsius.
- 6. U.S. Pat. No. 6,407,850, entitled "AUTO TILT STAGE," discloses a device for tilting a sample stage to multiple positions. The present invention does not tilt a sample stage to multiple positions.
- 7. In a book entitled "Scanning Electron Microscopy and X-ray Microanalysis, a Text for Biologists, Materials Scientists, and Geologists, 2Ed.," by Joseph I. Goldstein et al., published in 1992, pps. 267-270, it was disclosed that the resolution of a STEM may be achieved in a SEM by mounting a thin sample of the item to be viewed across an opening in a sample stage, placing either a scintillator coupled to a light pipe or a solid-state detector below the sample stage. The disadvantages of this method are that lateral scattering of electrons passing through the sample will determine the upper limit of image resolution and placing a scintillator and light-pipe or solid-state device under the sample stage requires modifications to the SEM which result in time-consuming setup procedures. Goldstein et al. also suggests using a tilted scattering surface of a high-atomic number. The disadvantage of this method is that lateral scattering of electrons passing through the sample will determine the upper limit of image resolution.